

UNITED STATES PATENT AND TRADEMARK OFFICE



UNITED STATES DEPARTMENT OF COMMERCE United States Patent and Trademark Office Address: COMMISSIONER FOR PATENTS P.O. Box 1450 Alexandria, Virginia 22313-1450 www.uspto.gov

APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.	
10/080,537	02/25/2002	Fuyuhiko Inoue	220033US2	8276	
22850	22850 7590 10/28/2004			EXAMINER	
OBLON, SPIVAK, MCCLELLAND, MAIER & NEUSTADT, P.C. 1940 DUKE STREET ALEXANDRIA, VA 22314			STAFIRA, MICHAEL PATRICK		
			ART UNIT	PAPER NUMBER	
			2877	·	

DATE MAILED: 10/28/2004

Please find below and/or attached an Office communication concerning this application or proceeding.

Supplemental Notice of Allowability

Application No.	Applicant(s)	
10/080,537	INOUE ET AL.	
Examiner	Art Unit	
Michael P. Stafira	2877	

			1
	Michael P. Stafira	2877	
The MAILING DATE of this communication appear All claims being allowable, PROSECUTION ON THE MERITS IS (0 herewith (or previously mailed), a Notice of Allowance (PTOL-85) of NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RIGOR of the Office or upon petition by the applicant. See 37 CFR 1.313	OR REMAINS) CLOSED in this apport of the appropriate communication GHTS. This application is subject to	olication. If not includ will be mailed in due	ed course. THIS
1. This communication is responsive to <u>RCE Flled 6/21/2004</u> .			
2. ☑ The allowed claim(s) is/are <u>1-31</u> .			
3. X The drawings filed on 25 February 2002 are accepted by the	e Examiner.		
 4. Acknowledgment is made of a claim for foreign priority under a) All b) Some* c) None of the: Certified copies of the priority documents have It Certified copies of the priority documents have It Copies of the certified copies of the priority documents have It Copies of the certified copies of the priority documents have It Copies of the certified copies of the priority documents have It Certified copies not received: Applicant has THREE MONTHS FROM THE "MAILING DATE" on noted below. Failure to timely comply will result in ABANDONMETHIS THREE-MONTH PERIOD IS NOT EXTENDABLE. 	been received. been received in Application No uments have been received in this i	national stage applica	
5. A SUBSTITUTE OATH OR DECLARATION must be submitt INFORMAL PATENT APPLICATION (PTO-152) which gives			NOTICE OF
 6. CORRECTED DRAWINGS (as "replacement sheets") must (a) including changes required by the Notice of Draftspersor 1) hereto or 2) to Paper No./Mail Date (b) including changes required by the attached Examiner's Paper No./Mail Date Identifying indicia such as the application number (see 37 CFR 1.8 each sheet. Replacement sheet(s) should be labeled as such in the 7. DEPOSIT OF and/or INFORMATION about the deposent attached Examiner's comment regarding REQUIREMENT F 	Amendment / Comment or in the drawing header according to 37 CFR 1.121(control of the control of th	office action of ags in the front (not the d).	
 Attachment(s) 1. ☑ Notice of References Cited (PTO-892) 2. ☐ Notice of Draftperson's Patent Drawing Review (PTO-948) 3. ☐ Information Disclosure Statements (PTO-1449 or PTO/SB/08 Paper No./Mail Date	5. ☐ Notice of Informal P 6. ☐ Interview Summary Paper No./Mail Dat 7. ☐ Examiner's Amendr 8. ☒ Examiner's Stateme 9. ☐ Other	(PTO-413), e nent/Comment	·

U.S. Patent and Trademark Office PTOL-37 (Rev. 1-04)

DETAILED ACTION

Priority

Receipt is acknowledged of papers submitted under 35 U.S.C. 119(a)-(d), which papers 1. have been placed of record in the file.

Allowable Subject Matter

- Claims 1-31 are allowed over the prior art of record. 2.
- The following is an examiner's statement of reasons for allowance: 3.

Regarding claims 1, the prior art fails to disclose or make obvious a wave-front aberration measuring method having the steps of measuring aberration components of a first set of orders out of a plurality of aberration components obtained by expanding the wave-front aberration of the optical system using a predetermined basis and calculating correction information for aberration components of a second set of orders, based on an aberration component of a predetermined order out of the measured aberration components of the first set of orders, and in combination with the other recited limitations of claims 1. Claims 2-7 are allowed by the virtue of dependency on the allowed claims 1.

Regarding claim 8, the prior art fails to disclose or make obvious a wave-front aberration measuring apparatus which measures a wave-front aberration of an optical system having a storage unit that stores correction information for aberration components of a second set of orders, the correction information being calculated based on an aberration component of a predetermined order out of aberration components of a first set of orders out of a plurality of

Application/Control Number: 10/080,537

Art Unit: 2877

aberration components obtained by expanding the wave-front aberration of the optical system using a predetermined basis, and in combination with the other recited limitations of claim 8.

Claims 9-15 are allowed by the virtue of dependency on the allowed claim 8.

Regarding claim 16, the prior art fails to disclose or make obvious a wave-front aberration measuring method with which to measure wave-front aberration of a projection optical system that projects a pattern onto a substrate having the steps of measuring aberration components of a second set of orders out of aberration components of a first set of orders included in wave-front aberration of said projection optical system; and correcting said measured aberration components of said second set of orders, based on a predetermined order that is included in aberration components of said first set of orders and not included in aberration components of said second set of orders, and in combination with the other recited limitations of claim 16. Claims 17-23 are allowed by the virtue of dependency on the allowed claim 16.

Regarding claim 24, the prior art fails to disclose or make obvious a wave-front aberration measuring apparatus which measures wave-front aberration of a projection optical system that projects a pattern onto a substrate having a measuring system arranged in said projection optical system, which measures aberration components of a second set of orders out of aberration components of a first set of orders included in wave-front aberration of said projection optical system; and a correcting unit coupled to said measuring system, which corrects said measured aberration components of said second set of orders, based on a predetermined order that is included in aberration components of said first set of orders and not included in aberration components of said second set of orders, and in combination with the other recited limitations of claim 24. Claims 25-31 are allowed by the virtue of dependency on the allowed claim 24.

Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Michael P. Stafira whose telephone number is 571-272-2430. The examiner can normally be reached on 4/10 Schedule Mon.-Thurs..

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Gregory Toatley can be reached on 571-272-2059. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

Michael F. Stafira Primary Examiner Art Unit 2877